

2014 EUVL Symposium, Oct 27-29, Washington DC.

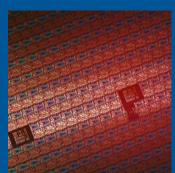
Accelerating the next technology revolution

Novel patterning materials research at SEMATECH: current status and future outlook

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Introduction



- EUV and high volume manufacturing
- SEMATECH novel resist programs:
 - Nanoparticle resist
 - Molecular organometallic resist
 - Negative tone resist (focus of another talk)
- Path towards volume manufacturing
- Summary

Pathfinding to HVM



1. Pathfinding:

- 1. New materials system
- 2. Understanding mechanism
- 3. most of university research

2. Pre-Development/Development

- Process parameters/properties: Outgassing/shelf-life
- II. Manufacturing compatibility
- 3. Enable the supply chain for early adoption

High volume manufacturing



Transistor
density/clock
speed: high
resolution

Timing matching: low LER

Tool
compatibility
contamination
: outgassing/
metal
contamination

High throughput: low dose

Logistics complexity: Shelf life

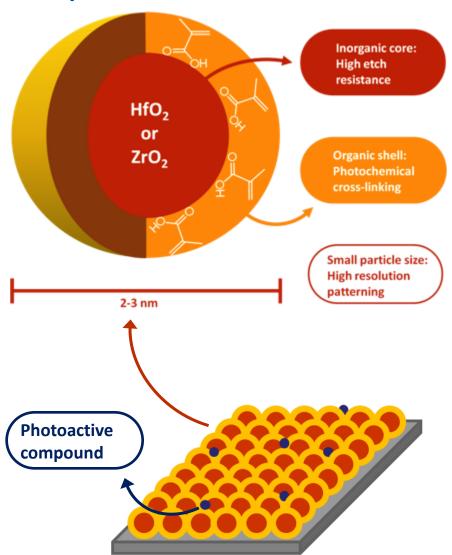
Environme ntal / Health effect

Why nanoparticle resists

- SEMATECH
- High sensitivity to EUV dose (1-3mJ/cm2, compared to 20 mJ/cm2 or higher for conventional EUV resists).
 - This is important particularly since there are still challenges associated with having a sufficiently high power EUV source
- The etch selectivity of these materials are high (almost 10:1) due to metal content.
 - This enables migration to thinner resist and therefore potentially higher resolution.
- SEMATECH and Cornell is scaling up batches of few baseline resists to study batch-to-batch variations and self-life
- SEMATECH is also engaged in studying EHS characteristics of this resist system (with University of Arizona).

Nanoparticle resist





Hybrid organic/inorganic nanoparticles:

Metal oxide with organic surface ligands

Inorganic core:

ZrO₂ or HfO₂, other metal oxides can be used.

Ligand Surface:

Carboxylate, phosphonate and sulfate studied to date

Photoactive Compounds:

Either PAG or photoradical generator

NOT CHEMICALLY AMPLIFIED

Nanoparticle resist (pathfinding)



- Work carried out in Cornell University
- High dose sensitivity (~3-4 mJ) resist system developed

materials	Dose(mJ/cm²)	Best resolution (CD and pitch) nm	LER(nm)	Image	comments
HfO2-Benzoate (7% non-ionic PAG)	15	22 (1:1)	3.4	100 pm	O-Xylene developer
ZrO2-benzoate (3% non-ionic PAG)	20	34 (1:2)	4.7		O-Xylene developer
HfO2-DMA (5 wt% non-ionic PAG)	2.2	20 (1:3)	6.1		4-methyl 2- pentanol developer
ZrO2-DMA (5 wt% non- ionic PAG)	1.4	20 (1:3)	6.6	200 m	4-methyl 2- pentanol developer

Nanoparticle resist system

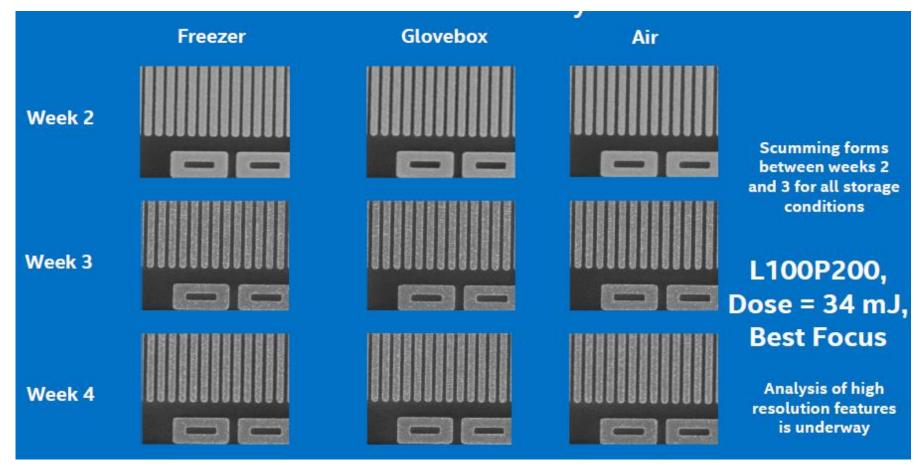


materials	Dose(mJ/cm²)	Best resolution (CD and pitch) nm	LER(nm)	Image	comments
Blend 1: ZrO2-MAA : ZrO2-DMA	2	26 (1:3)	6.0		4-methyl 2- pentanol developer
Blend 2: ZrO2-MAA : HfO2-DMA	2	26 (1:3)	7.5		4-methyl 2- pentanol developer
ZrO2-IBA (5 wt% non- ionic PAG)	2.6	30 (1:4)	6.9		4-methyl 2- pentanol developer
ZrO2-MAA (5 wt% non- ionic PAG)	4.2	22 (1:1)	5.6	MMT - MSC 2 ON 2 John SKIN 1 (MSC 2011 1 b) O	4-methyl 2- pentanol developer
HfO2-MAA (5 wt% non-ionic PAG)	4.2	24 (1:2)	4.9	MK-T 54800 T ON 2.3mm 48 O-1240011 1921	4-methyl 2- pentanol developer

Nanoparticle resist: shelf-life



 Shelf life study: scumming between weeks 2 and 3: only particle aging studies: could be better for solution



Courtesy: Marie Krysak, Intel Corp.

Powder aging model for nanoparticles



1) Hydrolysis in the presence of water, acid

Condensation of neighboring destabilized particles leads to larger, insoluble particles responsible for scumming

Courtesy: Marie Krysak, Intel Corp.

Shelf life (Cornell)



- Resist solution
 - Exposed after 10 days and 45 days.
 - Loss of sensitivity, ranging from 5 mJ/cm2 to 15 mJ/cm2) in 6 weeks
 - Upper limit: but needs finer time scale.

EHS study of nanoparticles



Cytotoxicity

- Aerobic respiration testing
- Anaerobic methanogenic test
- Microtox assay
- Real time cell analysis

Microorganisms

Human cells

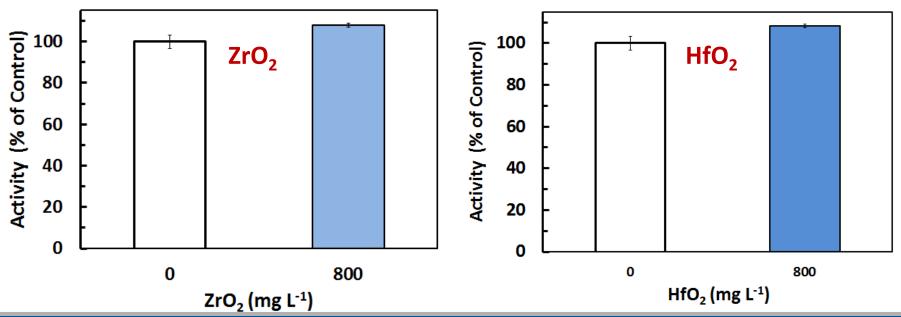
Nanoresist colloidal stability in bioassay medium

Particle size distribution and zeta potential

Release of soluble ligand from NP suspensions in bioassay medium

Data: Reyes Sierra, Univ of Arizona

Ligandless ZrO₂ and HfO₂ NPs: SEMATECH Methanogenic Toxicity Bioassays



- Ligandless ZrO₂ and HfO₂ nanoparticles didn't display microbial inhibition in aerobic and anaerobic bioassays at relatively high concentrations (up to 1200 mg NPs/L)
- The nano-photoresists showed different inhibitory responses in the <u>Microtox</u> bioassay.

Data: Reyes Sierra, Univ of Arizona

Outgassing study of nanoparticles



- Outgassing study ongoing(at IMEC)
- First indication is encouraging: comprehensive data next week.



Full Field exposure



- So far system exposed on Microexposure Tool(MET)
- Necessary to expose on a HVM platform such as NXE
 - understand resist patterning mechanism in order to accelerate the HUV insertion timeline
- Exposure on NXE 3100 is being planned (in cooperation with IMEC)
 - Metal contamination study using ICP is done:
 - Contamination in the order of 100ppb is observed for NA, Cd, Hf. Rest are below 10 ppb
 - Outgas testing conducted (at IMEC)
 - Process window data
 - Build physical resist model
 - Batches of 100 ml samples are prepared for exposure on NXE 3100



Process flow Characterize metal **SEMATECH** contamination Expose on NXE3100(Baseline nanoparticle test reticle with resist selection based Perform outgas test adequate design on prior work space) Determine shelf-life Collect CD/LER data over several dies with different dose/focus Model Physical model Data analysis/Initial refinement/New verification model build models Resist parameter measurements



Molecular Organometallic EUV resist

MORE project



- Three years of work under SEMATECH /Intel sponsorship:
 - approximately 500 different compositions characterized.
- Synthesized and evaluated ~500 compounds for:
 - Coating quality
 - EUV sensitivity
 - Imaging characteristics
 - Evaluated compounds containing: Cr, Co, Fe, Cu, Ni, Sn, Bi, Te, Sb

Successes:

- Several compounds capable of 18-nm resolution
 - High dose sensitivity: ~6mJ
 - Low LER: ~<2nm
- Identified trends to assist in further improvements.
- Progress is being made towards outgas testing and shelf-life optimization
- Critical for supply chain to adopt the technology.

Molecular Organometallic Resists for EUV (MORE) SEMATECH

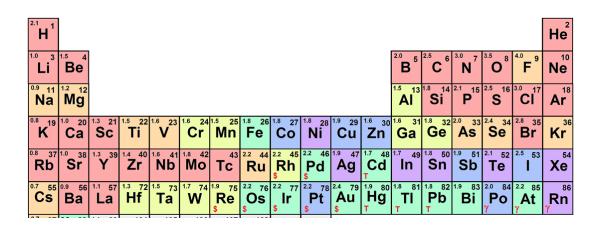
As EUV resolution improves, resists will be thinner. Traditional elements will no longer be able to stop enough EUV light for good photon statistics. Therefore, we are investigating elements in the periodic table with high EUV OD.

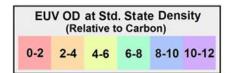
We hope to Share Advantages of the Inpria/Cornell HfO₂ Resists:

- High EUV OD.
- High stopping power of secondary electrons (less electron blur).
- Excellent etch resistance.

We hope: to have better control of performance by using a broader range of materials.

To date, we have synthesized and screened ~500 organometallic compounds.

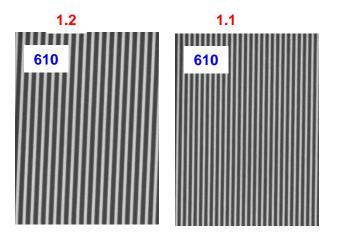




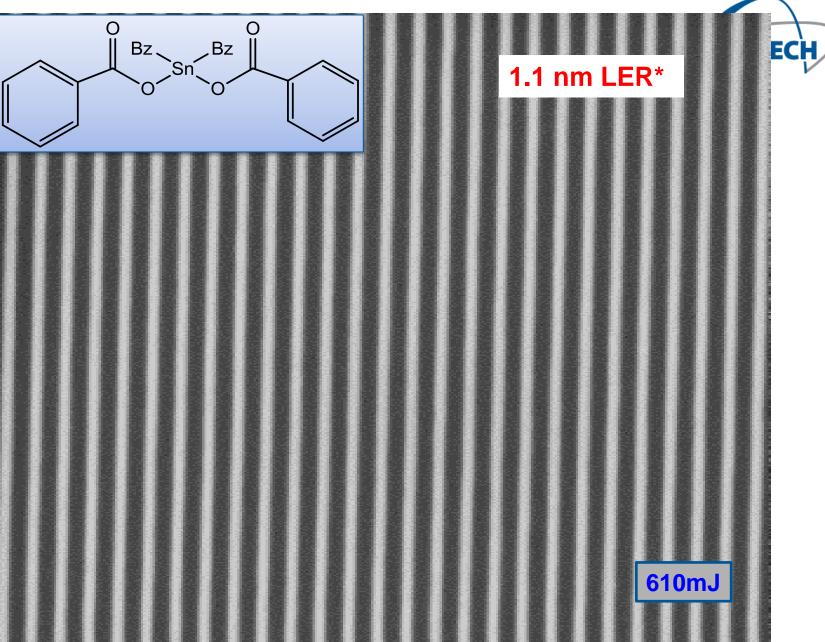
MORE



- High speed group: dose 6-9 mJ/cm2: Sb-based
- Low LER compound: < 2nm, Sn-based



- Positive tone Pd/Pt group:
- Oxalate ligand group:
 - Focus of this talk





IV. Focus on Oxalate Complexes



Metal oxalates have a well-characterized photochemistry, resulting in a loss of CO₂ and opening two binding sites for cross-linking.

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We have prepared 30 different oxalate complexes for testing which allows us to systematically explore variables such as:

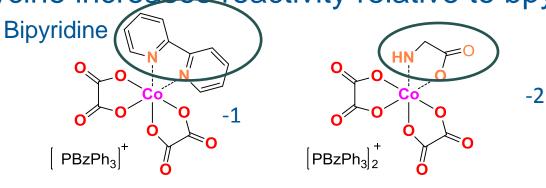
- Central metal
- Oxalate loading
- Bipyridine vs. acetylacetonate vs. glycine

IV. Oxalate Trends

Trend #1: More oxalate, more negative the complex = faster resist

Trend #2: $Co \ge Fe > Cr$

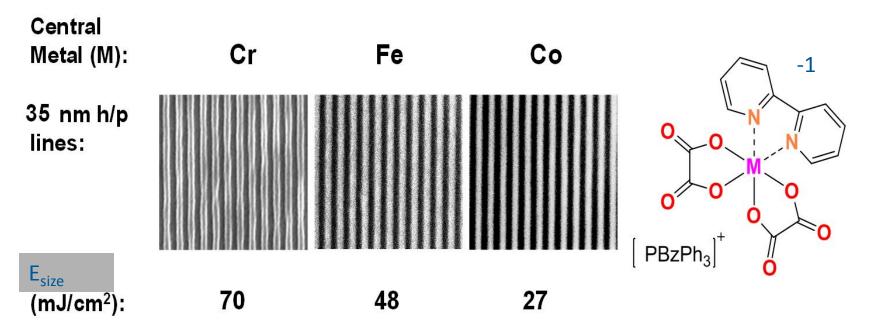
Trend #3: Glycine increases reactivity relative to bpy



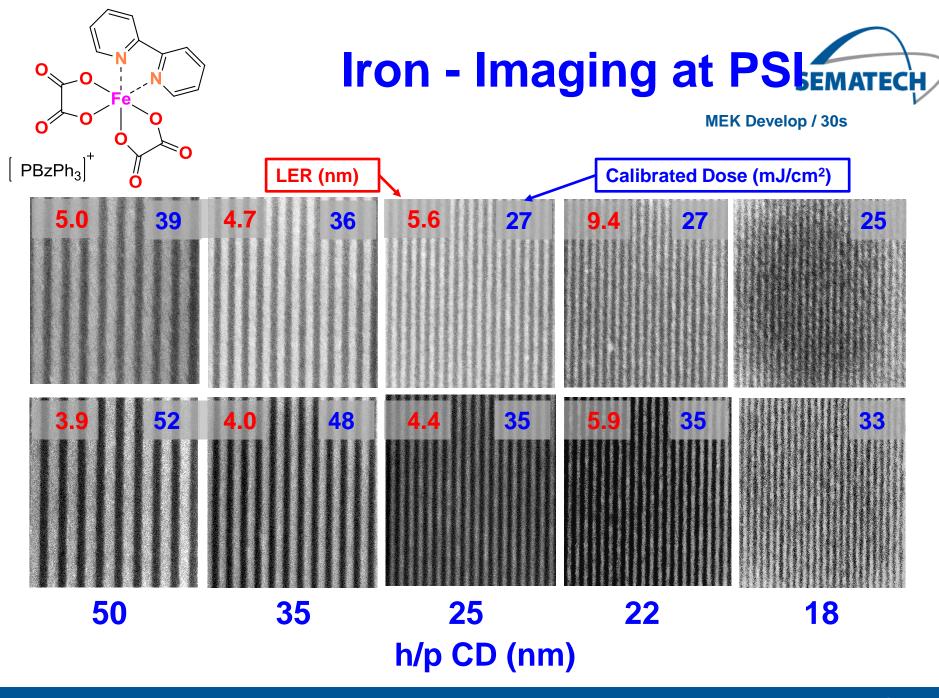
$$E_{\text{max}} = 8 \text{ mJ/cm}^2$$

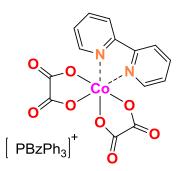
$$E_{max} = 4 \text{ mJ/cm}^2$$

IV. Imaging with Oxalate Compounds SEMATECH



- Best results were with 2 oxalates and 1 bipyridine.
- Compounds with <2 oxalates are too slow.
- M(oxalate)₃ complexes appear to be too reactive.





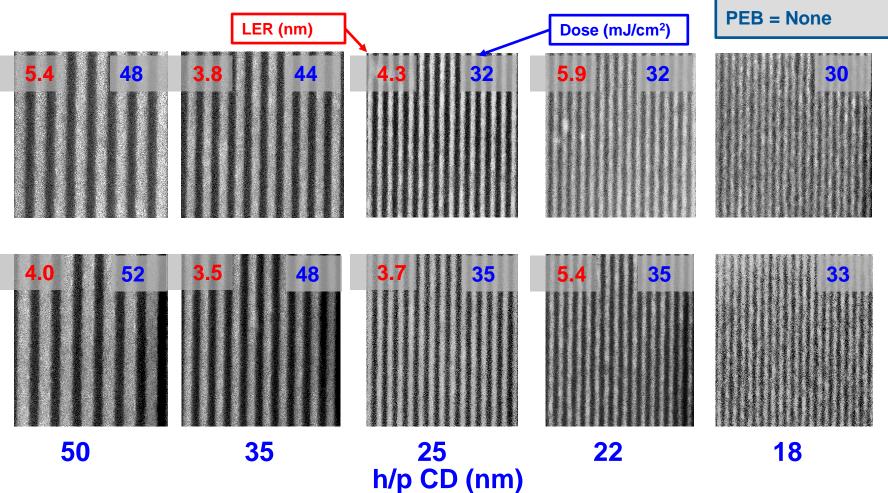
Cobalt – Imaging at PSI



Dev. = MEK/15s

Thickness = 29nm

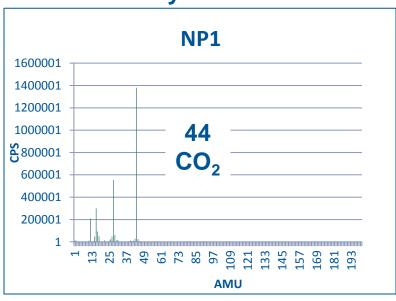
 $PAB = 90^{\circ}/60s$



BTP[Co(bpy)(ox)₂] Shelf-Live and Outgassing



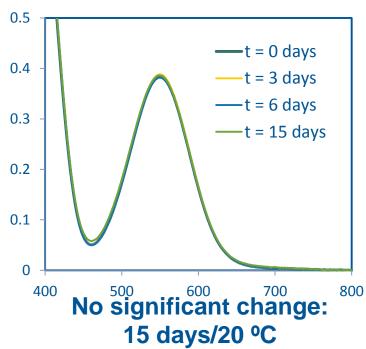
Passes Outgassing Tests by ~2X



 CO_2 (m/e = 44) is the largest peak

Witness plate is underway.

1% solution BTP[Co(ox)₂(bpy)] in 66/33 ethyl lactate/CH₃CN. Absorption vs. wavelength



Metal-Organic resist



- Manufacturing consideration
 - Shelf-life: very good
 - Low sensitivity to out of band radiation
 - Low outgassing

Next step



- Enable the supply chain to adopt the new materials
 - Establish stable baseline, understand mechanism.
 - Outgas study, shelf-life characterization, fullfiled exposure are steps towards this goal
 - Involves supply chain players

Summary



- In last few years SEMATECH has been working on pathfinding of novel metal-based resist systems
- Efforts are being undertaken to evaluate identified baseline resist in novel space for compatibility with high volume manufacturing
- Transition to full-field lithographic characterization is underway for nanoparticle resist.
- SEMAETCH is actively involved with supply chain to enable them to adopt the early technology for further improvement.

Acknowledgement



- IMEC: for their support for NXE3100 exposure
- INTEL: Marie Krysak for sharing shelf life data for nanoparticle resist
- University of Arizona (Reyes Sierra): For EHS study of the nanoparticles under SEMATECH sponsorship
- SUNY, New Paltz: Dan Freedman and his group: for oxalate work under SEMAETCH sponsorship
- SEMATECH: For sponsoring this work